

Enter your query below, and then click *Start Search*

(mems <or> mms <or> micromechanical <or> microelectromechanical)
<and> ((dry <or> plasma)<near/3>etch) <and> sacrificial

Start Search Clear

Collections to Search:

☒ Journals ☒ Conference Proceedings ☒ Standards

Additional Criteria:

☐ Match similar subject terms ☐ Latest additions to IEL

Publication Year(s): All ▼ to Present ▼

Results List: Sort by Score ▼ in Descending ▼ order

List 25 ▼ results at a time Display 5 ▼ line citation

If you have any question about IEL Online and how it works, check the Frequently Asked Questions or email [IEL Online Support](#).

To let us know what you think about IEL Online, email your comments to [IEEE Electronic Products](#)

| [IEL Online Home](#) | [Search](#) | [Advanced Search](#) | [What's New](#) | [Help](#) | [Logout](#) |
| [FAQ's](#) | [Support](#) | [Comments](#) |















Copyright 1999 Institute of Electrical and Electronics Engineers. All rights reserved.

(mems <or> mms <or> micromechanical <or> microelect) Refine

Collection: ☒ Journals ☒ Conferences ☒ Standards

Your search matched 18 of 671461 documents.

18 are presented on this page, sorted by Score in descending order.

DOC TYPE	VIEW ISSUE TOC	VIEW FULL PAGE	VIEW CITATION
PER			<p><u>Flexible, dry-released process for aluminum electrostatic actuators</u> Storment, C.W.; Borkholder, D.A.; Westerlind, V.; Suh, J.W.; Maluf, N.I.; Kovacs, G.T.A. Microelectromechanical Systems, Journal of Volume: 3 3 , Sept. 1994 , Page(s): 90 -96</p>
PER			<p><u>Dendritic material as a dry-release sacrificial layer</u> Hyuk-Jeen Suh; Bharathi, P.; Beebe, D.J.; Moore, J.S. Microelectromechanical Systems, Journal of Volume: 9 2 , June 2000 , Page(s): 198 -205</p>
CNF			<p><u>Microtechnologies for microsensors</u> Delapierre, G. Emerging Technologies and Factory Automation, 1995. ETFA '95, Proceedings., 1995 INRIA/IEEE Symposium on Volume: 2 , 1995 , Page(s): 275 vol.2</p>
CNF			<p><u>Dry releasing of electroplated rotational and overhanging structures</u> Hirano, T.; Furuhashi, T.; Fujita, H. Micro Electro Mechanical Systems, 1993, MEMS '93, Proceedings An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems. IEEE. , 1993 , Page(s): 278 -283</p>
CNF			<p><u>Characterization of molybdenum thin films for micromechanical structures</u> Brown, R.B.; Ger, M.-L.; Nguyen, T. Micro Electro Mechanical Systems, 1990. Proceedings, An Investigation of Micro Structures, Sensors, Actuators, Machines and Robots. IEEE , 1990 , Page(s): 77 -81</p>
PER			<p><u>High aspect-ratio combined poly and single-crystal silicon (HARPSS) MEMS technology</u> Ayazi, F.; Najafi, K. Microelectromechanical Systems, Journal of Volume: 9 3 , Sept. 2000 , Page(s): 288 -294</p>
PER			<p><u>Silicon micromechanics: sensors and actuators on a chip</u> Howe, R.T.; Muller, R.S.; Gabriel, K.J.; Trimmer, W.S.N.</p>

CNF



Thick Polycrystalline Silicon For Surface Micromechanical Applications: Deposition, Structuring And Mechanical Characterization

Lange, P.; Kirsten, M.; Riethmuller, W.; Wenk, B.; Zwicker, G.; Morante, J.R.; Ericson, F.; Schweitz, J.A.

Solid-State Sensors and Actuators, 1995 and Eurosensors IX. Transducers '95. The 8th International Conference on
Volume: 1 , Page(s): 202 -203

CNF



Low temperature sacrificial wafer bonding for planarization after very deep etching

Spiering, V.L.; Berenschot, J.W.; Elwenspoek, M.; Fluitman, J.H.J.
Micro Electro Mechanical Systems, 1994, MEMS '94, Proceedings, IEEE Workshop on , 1994 , Page(s): 69 -74

CNF



Process and design considerations for surface micromachined beams for a tuneable interferometer array in silicon

Aratani, K.; French, P.J.; Sarro, P.M.; Wolffenbuttel, R.F.; Middelhoek, S.

Micro Electro Mechanical Systems, 1993, MEMS '93, Proceedings An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems. IEEE. , 1993 , Page(s): 230 -235

CNF



Amorphous silicon carbide films by plasma-enhanced chemical vapor deposition

Tong, L.; Mehregany, M.; Tang, W.C.

Micro Electro Mechanical Systems, 1993, MEMS '93, Proceedings An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems. IEEE. , 1993 , Page(s): 242 -247

CNF



Single crystal silicon micro-actuators

Suzuki, K.

Electron Devices Meeting, 1990. Technical Digest., International , 1990 , Page(s): 625 -628

CNF



Integration of surface-micromachined zinc oxide sensors in n-well CMOS technology

Polla, D.L.; Yoon, H.; Tamagawa, T.; Voros, K.

Electron Devices Meeting, 1989. Technical Digest., International , 1989 , Page(s): 495 -498

CNF



Single crystal silicon rotational micromotors

Suzuki, K.; Tanigawa, H.

Micro Electro Mechanical Systems, 1991, MEMS '91, Proceedings. An Investigation of Micro Structures, Sensors, Actuators, Machines and Robots. IEEE , 1991 , Page(s): 15 -20

PER



Dry release for surface micromachining with HF vapor-phase etching

Lee, Y.-I.; Park, K.-H.; Lee, J.; Lee, C.-S.; Yoo, H.J.; Kim, C.-J.; Yoon, Y.-S.

Microelectromechanical Systems, Journal of
Volume: 6 3 , Sept. 1997 , Page(s): 226 -233

PER



Plasma planarization for sensor applications

Li, Y.X.; French, P.J.; Wolffenbuttel, R.F.

Microelectromechanical Systems, Journal of
Volume: 4 3 , Sept. 1995 , Page(s): 132 -138

PER



Sacrificial wafer bonding for planarization after very deep etching

Spiering, V.L.; Berenschot, J.W.; Elwenspoek, M.; Fluitman, J.H.J.

Microelectromechanical Systems, Journal of
Volume: 4 3 , Sept. 1995 , Page(s): 151 -157

PER



Characterization of AlGaAs microstructure fabricated by AlGaAs/GaAs micromachining

Uenishi, Y.; Tanaka, H.; Ukita, H.

Electron Devices, IEEE Transactions on
Volume: 41 10 , Oct. 1994 , Page(s): 1778 -1783

| [IEL Online Home](#) | [Search](#) | [Advanced Search](#) | [What's New](#) | [Help](#) | [Logout](#) |
| [FAQ's](#) | [Support](#) | [Comments](#) |

Copyright 1999 Institute of Electrical and Electronics Engineers. All rights reserved.

L Number	Hits	Search Text	DB	Time stamp
1	647	(dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:00
8	201	((dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)) and (sealed cavity encapsulated enclosed hermetic hermetically)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 11:56
15	109	((dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)) and (sealed cavity encapsulated enclosed hermetic hermetically)) and @ad<20000530	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 11:57
22	59	((dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)) and (sealed cavity encapsulated enclosed hermetic hermetically)) and @riad<20000530	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 11:57
29	135	((dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)) and (sealed cavity encapsulated enclosed hermetic hermetically)) and @ad<20000530 (((dry adj3 (etch\$3 plasma releas\$3)) near15 (MEMS microelectro microstructure microfabricat\$3 micro)) and (sealed cavity encapsulated enclosed hermetic hermetically)) and @riad<20000530)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 11:57
36	16	6174820.URPN.	USPAT	2003/07/12 12:39
37	5	("5798283" "5963788" "6012336" "6159762" "6174820").PN.	USPAT	2003/07/12 12:42
38	10	5683591.URPN.	USPAT	2003/07/12 13:34
39	30	5417235.URPN.	USPAT	2003/07/12 13:42
40	3784	(seal\$3) near15 (MEMS microelectro microstructure micromachin\$3 microfabricat\$3 micro)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:01
47	64	((seal\$3) near15 (MEMS microelectro microstructure micromachin\$3 microfabricat\$3 micro)) and ((resist photoresist organic polymer polymeric polyimide PMMA polymethylmethacrylate acrylate resin) near12 (temporary sacrificial))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:23
54	10	"6194722"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:27
61	6	"6274462"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:27
68	31	5427975.URPN.	USPAT	2003/07/12 15:18

Welcome to IEEE Xplore

- ☐ Home
- ☐ What Can I Access?
- ☐ Log-out


Tables of Contents

- ☐ Journals & Magazines
- ☐ Conference Proceedings
- ☐ Standards

Search

- ☐ By Author
- ☐ Basic
- ☐ Advanced

Member Services

- ☐ Join IEEE
 - ☐ Establish IEEE Web Account
 - ☐ Access the IEEE Member Digital Library
-  Print Format

Your search matched **49** of **951805** documents.

A maximum of **49** results are displayed, **15** to a page, sorted by **Relevance** in **descending** order.
You may refine your search by editing the current search expression or entering a new one in the text box.
Then click **Search Again**.

dry<near>release

Search Again

Results:

Journal or Magazine = **JNL** Conference = **CNF** Standard = **STD**

1 A dry-release method based on polymer columns for microstructure fabrication

Mastrangelo, C.H.; Saloka, G.S.;

Micro Electro Mechanical Systems, 1993, MEMS '93, Proceedings 'An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems'. IEEE. , 7-10 Feb. 1993.
Page(s): 77 -81

[\[Abstract\]](#) [\[PDF Full-Text \(484 KB\)\]](#) **IEEE CNF**

2 Dry releasing of electroplated rotational and overhanging structures

Hirano, T.; Furuhashi, T.; Fujita, H.;

Micro Electro Mechanical Systems, 1993, MEMS '93, Proceedings 'An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems'. IEEE. , 7-10 Feb. 1993.
Page(s): 278 -283

[\[Abstract\]](#) [\[PDF Full-Text \(616 KB\)\]](#) **IEEE CNF**

3 High performance microwave air-bridge resonators

Seabury, C.W.; Cheung, J.T.; Kobrin, P.H.; Addison, R.; Havens, D.P.;

Ultrasonics Symposium, 1995. Proceedings., 1995 IEEE , Volume: 2 , 7-10 Nov. 1995.
Page(s): 909 -911 vol.2

[\[Abstract\]](#) [\[PDF Full-Text \(220 KB\)\]](#) **IEEE CNF**

4 Fabrication of surface micromachined polysilicon actuators using dry release process of HF gas-phase etching

Jong Hyun Lee; Hoi Hwan Chung; Seung Youl Kang; Jong Tae Baek; Hyung Joun Kim;

Electron Devices Meeting, 1996., International , 8-11 Dec. 1996

Page(s): 761 -764

[\[Abstract\]](#) [\[PDF Full-Text \(792 KB\)\]](#) **IEEE CNF**

5 Electrostatic surface drives: theoretical considerations and fabrication

Hoehn, S.; Merchant, P.; Koke, G.; Williams, J.;

Solid State Sensors and Actuators, 1997. TRANSDUCERS '97 Chicago., 1997

International Conference on , Volume: 1 , 16-19 June 1997

Page(s): 41 -44 vol.1

[\[Abstract\]](#) [\[PDF Full-Text \(520 KB\)\]](#) **IEEE CNF**

6 Dendritic materials as a dry release sacrificial layer

Suh, H.; Bharathi, P.; Moore, J.; Beebe, D.J.;

Micro Electro Mechanical Systems, 1999. MEMS '99. Twelfth IEEE International

Conference on , 17-21 Jan. 1999

Page(s): 200 -204

[\[Abstract\]](#) [\[PDF Full-Text \(576 KB\)\]](#) **IEEE CNF**

7 Fully integrated micromachined capacitive switches for RF applications

Park, J.Y.; Kim, G.H.; Chung, K.W.; Bu, J.U.;

Microwave Symposium Digest., 2000 IEEE MTT-S International , Volume: 1 , 11-

June 2000

Page(s): 283 -286 vol.1

[\[Abstract\]](#) [\[PDF Full-Text \(400 KB\)\]](#) **IEEE CNF**

8 Electroplated rf MEMS capacitive switches

Park, J.Y.; Kim, G.H.; Chung, K.W.; Bu, J.U.;

Micro Electro Mechanical Systems, 2000. MEMS 2000. The Thirteenth Annual

International Conference on , 23-27 Jan. 2000

Page(s): 639 -644

[\[Abstract\]](#) [\[PDF Full-Text \(660 KB\)\]](#) **IEEE CNF**

9 High aspect-ratio dry-release poly-silicon MEMS technology for inertial microgyroscopes

Ayazi, F.; Najafi, K.;

Position Location and Navigation Symposium, IEEE 2000 , 13-16 March 2000

Page(s): 304 -308

[\[Abstract\]](#) [\[PDF Full-Text \(816 KB\)\]](#) **IEEE CNF**

10 Flexible, dry-released process for aluminum electrostatic actuators

Stormont, C.W.; Borkholder, D.A.; Westerlind, V.; Suh, J.W.; Maluf, N.I.; Kovacs G.T.A.;

Microelectromechanical Systems, Journal of , Volume: 3 Issue: 3 , Sept. 1994

Page(s): 90 -96

[\[Abstract\]](#) [\[PDF Full-Text \(832 KB\)\]](#) **IEEE JNL**

11 Dry release for surface micromachining with HF vapor-phase etching

Lee, Y.-I.; Park, K.-H.; Lee, J.; Lee, C.-S.; Yoo, H.J.; Kim, C.-J.; Yoon, Y.-S.;
Microelectromechanical Systems, Journal of , Volume: 6 Issue: 3 , Sept. 1997
Page(s): 226 -233

[\[Abstract\]](#) [\[PDF Full-Text \(148 KB\)\]](#) **IEEE JNL**

12 Dendritic material as a dry-release sacrificial layer

Hyuk-Jeen Suh; Bharathi, P.; Beebe, D.J.; Moore, J.S.;
Microelectromechanical Systems, Journal of , Volume: 9 Issue: 2 , June 2000
Page(s): 198 -205

[\[Abstract\]](#) [\[PDF Full-Text \(544 KB\)\]](#) **IEEE JNL**

13 Self-assembled fluorocarbon films for enhanced stiction reduction

Srinivasan, U.; Houston, M.R.; Rowe, R.T.; Maboudian, R.;
Solid State Sensors and Actuators, 1997. TRANSDUCERS '97 Chicago., 1997
International Conference on , Volume: 2 , 16-19 June 1997
Page(s): 1399 -1402 vol.2

[\[Abstract\]](#) [\[PDF Full-Text \(520 KB\)\]](#) **IEEE CNF**

14 High aspect ratio Si etching technique and application

Dacleng Zhang; Jianwei Wan; Guizheng Yan; Ting Li; Dayu Tian; Ke Deng;
Solid-State and Integrated Circuit Technology, 1998. Proceedings. 1998 5th
International Conference on , 21-23 Oct. 1998
Page(s): 91 -93

[\[Abstract\]](#) [\[PDF Full-Text \(172 KB\)\]](#) **IEEE CNF**

15 A 1 mG lateral CMOS-MEMS accelerometer

Luo, H.; Fedder, G.K.; Carley, L.R.;
Micro Electro Mechanical Systems, 2000. MEMS 2000. The Thirteenth Annual
International Conference on , 23-27 Jan. 2000
Page(s): 502 -507

[\[Abstract\]](#) [\[PDF Full-Text \(488 KB\)\]](#) **IEEE CNF**

[1](#) [2](#) [3](#) [4](#) [\[Next\]](#)

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#)
[Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#)
[No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)